



Nanomaterials for Micro/Nano Devices

Guest Editor:

Dr. Amir Hussain Idrisi
Department of Mechanical
Engineering-Engineering
Mechanics, Michigan
Technological University,
Houghton, MI 49931, USA

Deadline for manuscript
submissions:

closed (20 April 2024)

Message from the Guest Editor

Dear Colleagues,

Nanomaterials are chemical substances or materials consisting of very small particles of different shapes and sizes. They occur in nature or can be deliberately manufactured and engineered to generate materials which exhibit novel characteristics. Materials engineered to such a small scale are often referred to as engineered nanomaterials (ENMs) and can take on unique mechanical, chemical, optical, magnetic, electrical, and other properties. These emergent products have the potential for great impacts in electronics, medicine, and other fields.

The present Special Issue of Micromachines focuses on the nanomaterials for Micro/Nano Devices. This Special Issue aims to review the current state of the art and utilization of new synthesis techniques, characterizing methods, and integration strategies to develop nanomaterial-based devices with improved performance and functionality. We invite original research articles, review articles, and perspectives on recent developments in the field of nanomaterials for micro/nano devices.





an Open Access Journal by MDPI

Editor-in-Chief

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Contact Us

Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
[X@micromach_mdpi](https://twitter.com/micromach_mdpi)